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Tateno et al.

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(54) **VAPORIZER FOR SUBSTRATE PROCESSING APPARATUS**

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(**) Term: **14 Years**

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(30) **Foreign Application Priority Data**

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(51) **LOC (10) Cl.** **13-03**

(52) **U.S. Cl.**
USPC **D13/182**

(58) **Field of Classification Search**
USPC D13/158, 177, 182, 184; D15/144, D15/144.1, 144.2, 199; 414/935–941, 217, 414/147
See application file for complete search history.

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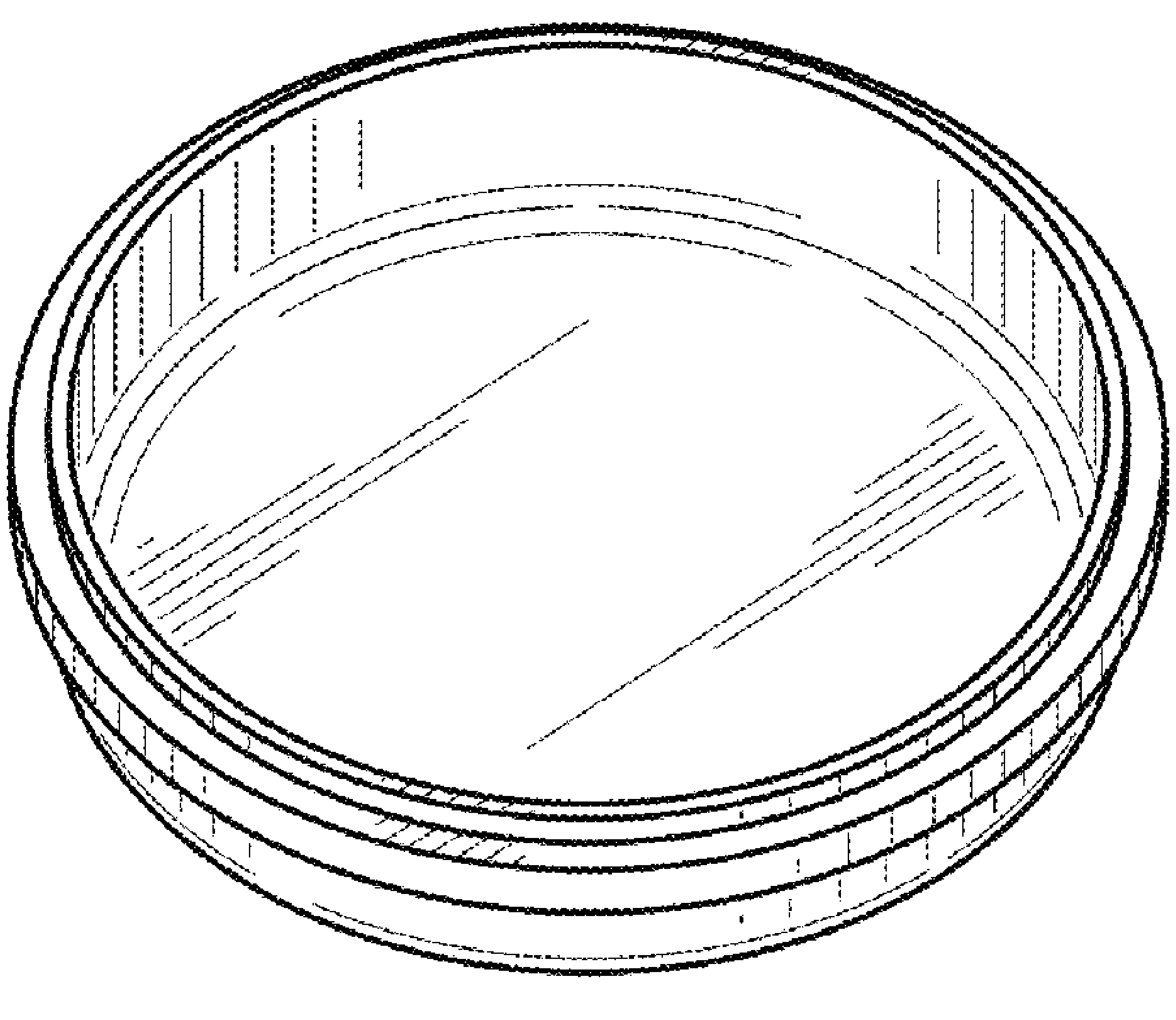
(57) **CLAIM**

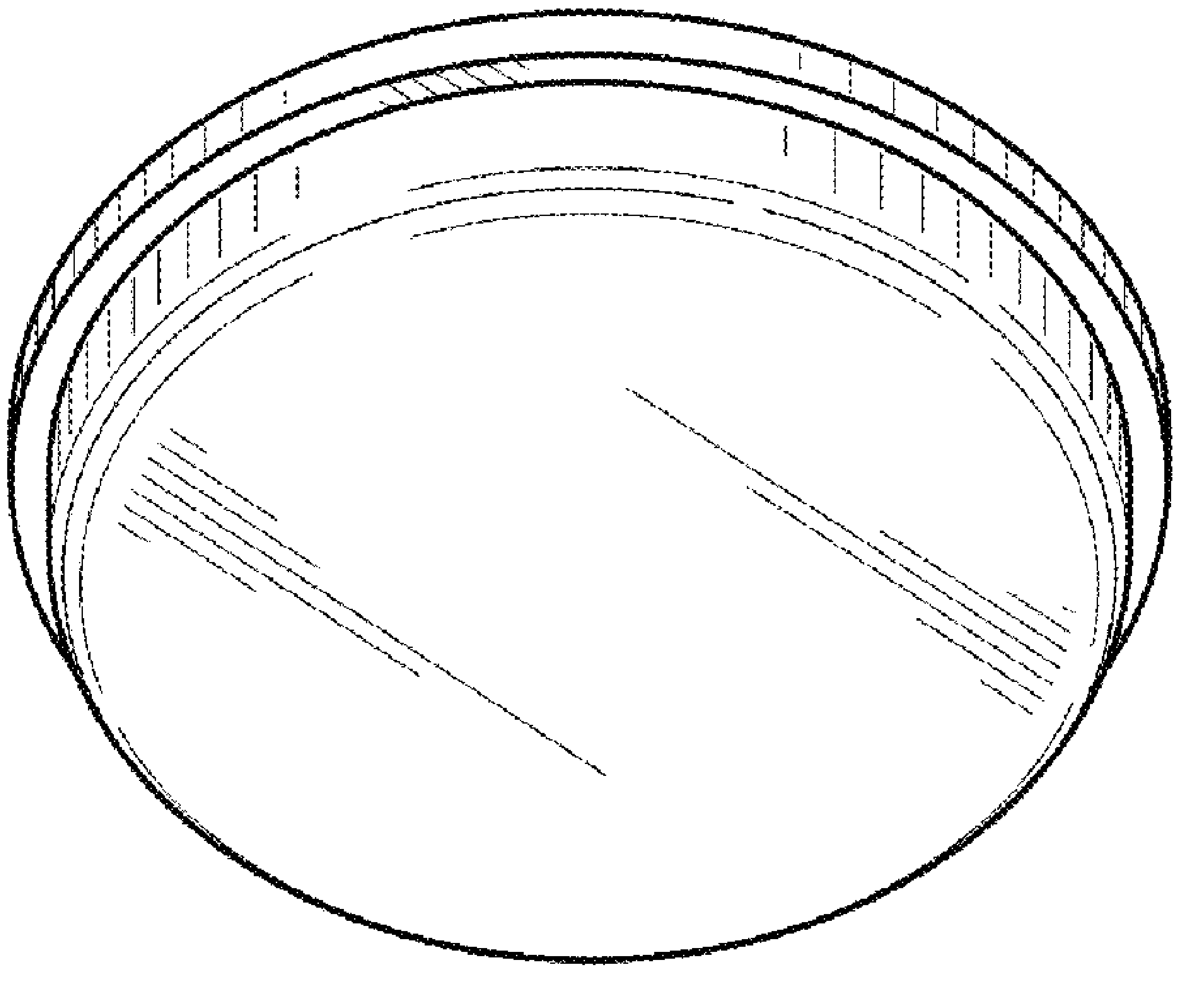
The ornamental design for a vaporizer for substrate processing apparatus, as shown and described.

DESCRIPTION

FIG. **1** is a front, perspective view of a vaporizer for substrate processing apparatus showing our new design;
FIG. **2** is a front, bottom perspective view thereof;
FIG. **3** is a front elevational view thereof, the back elevation view being the same therefore omitted;
FIG. **4** is a left side elevational view thereof, the right side elevation view being the same therefore omitted;
FIG. **5** is a top plan view thereof;
FIG. **6** is a bottom plan view thereof; and,
FIG. **7** is a cross-sectional view taken along line **7**-**7** in FIG. **5**.
The back elevational view is the same as the front elevational view and has, therefore, been omitted; the right side elevational view is the same as the left side elevational view and has, therefore been omitted.

1 Claim, 1 Drawing Sheet





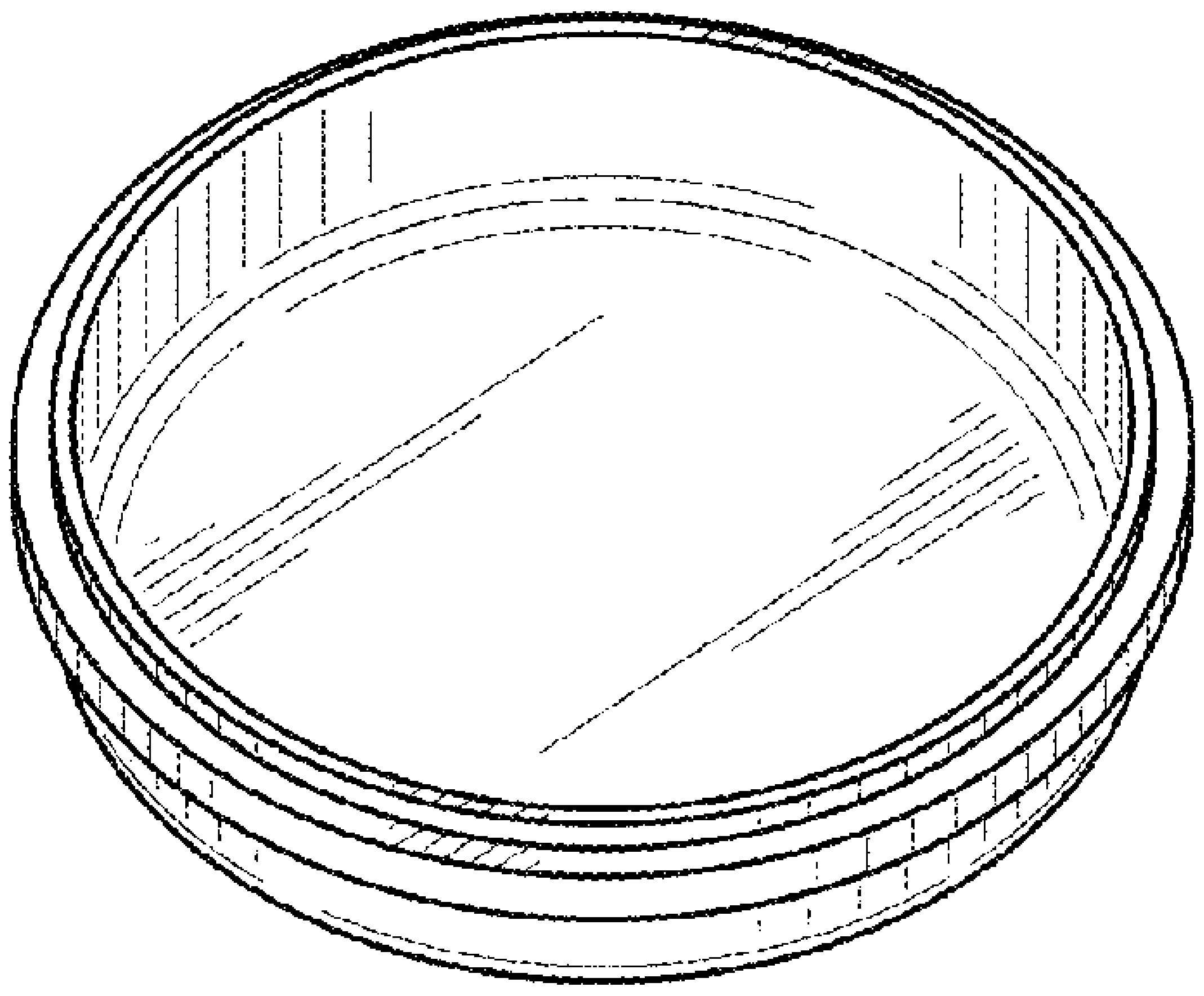


FIG. 1

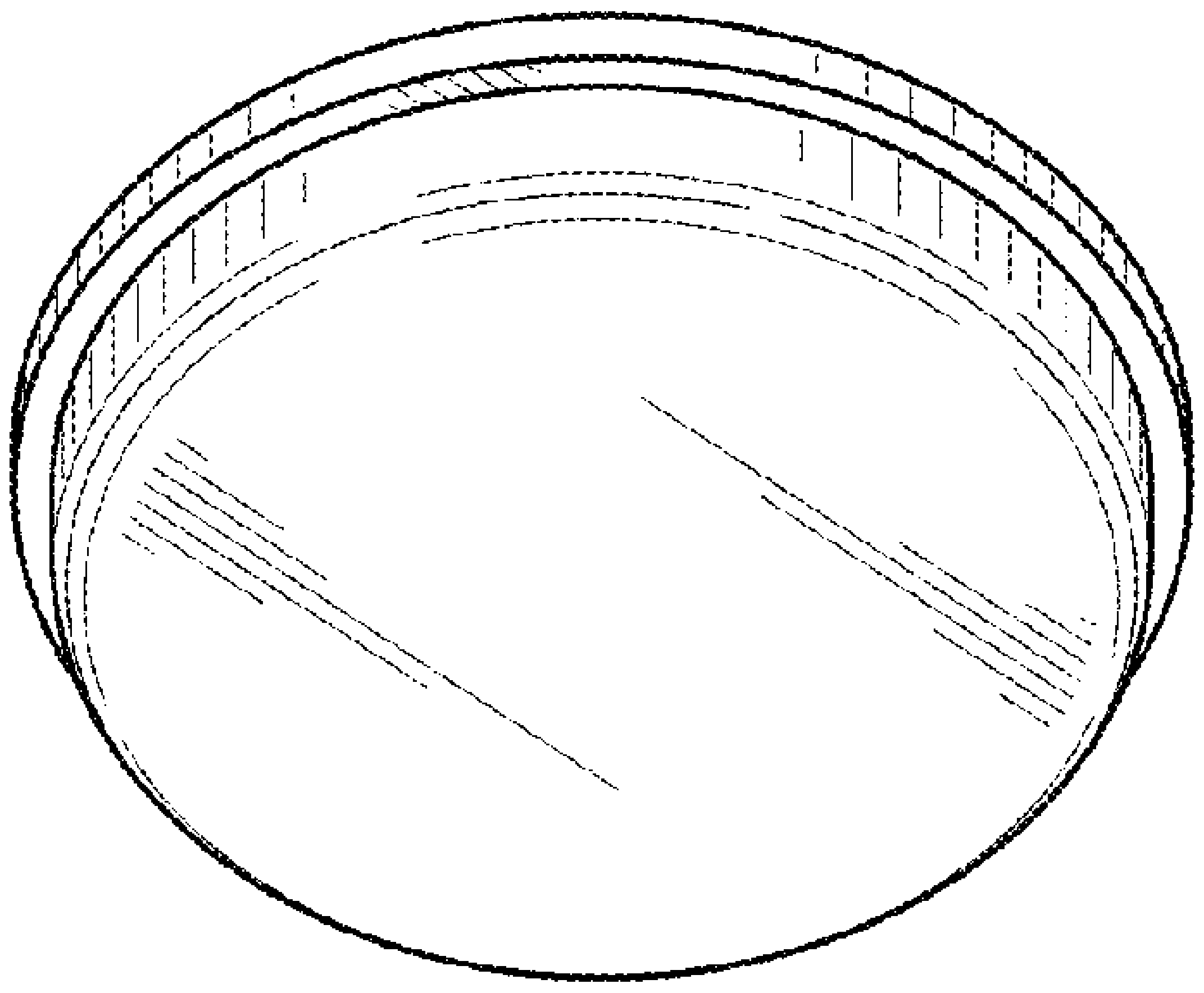


FIG. 2

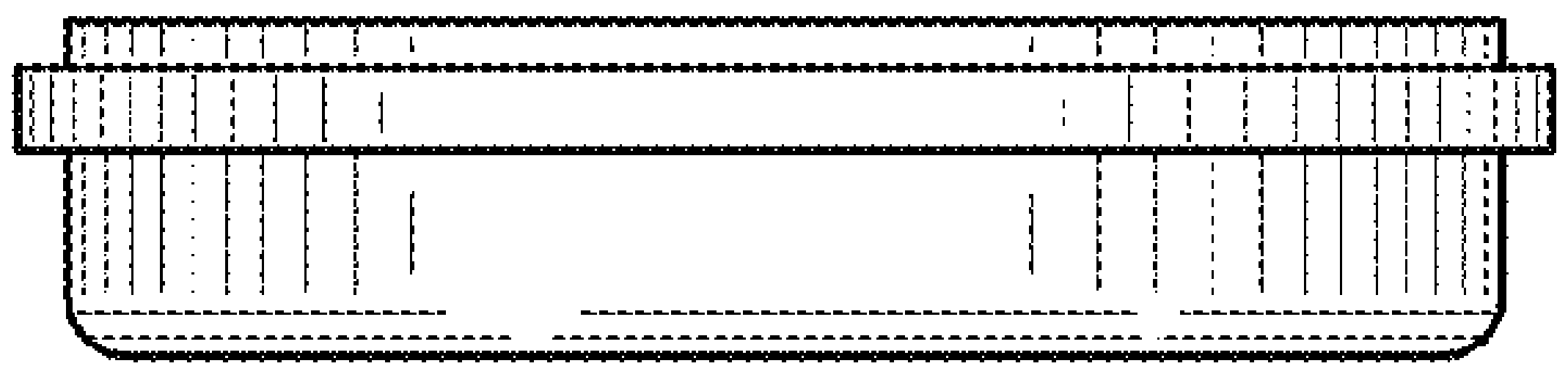


FIG. 3

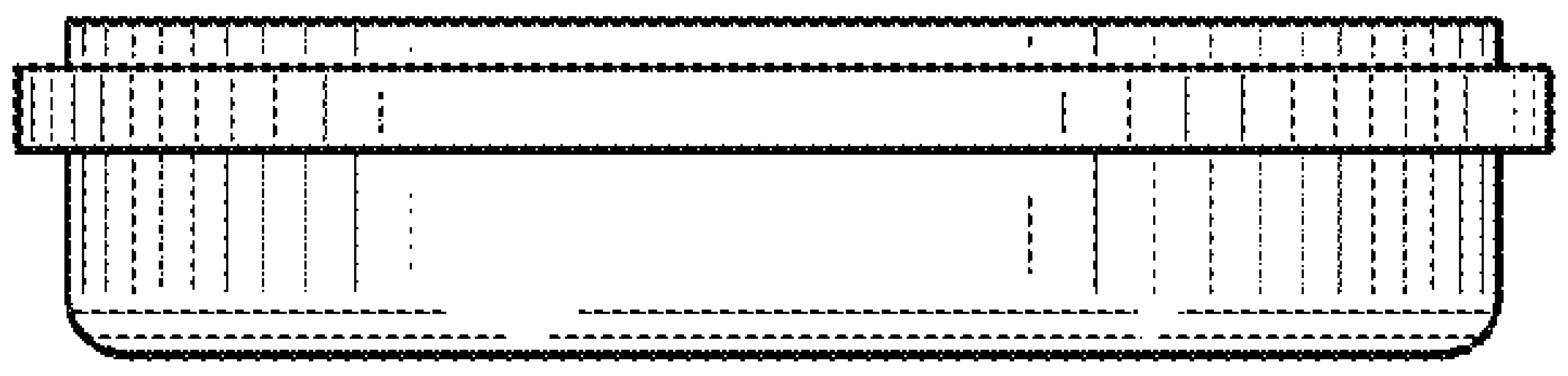


FIG. 4

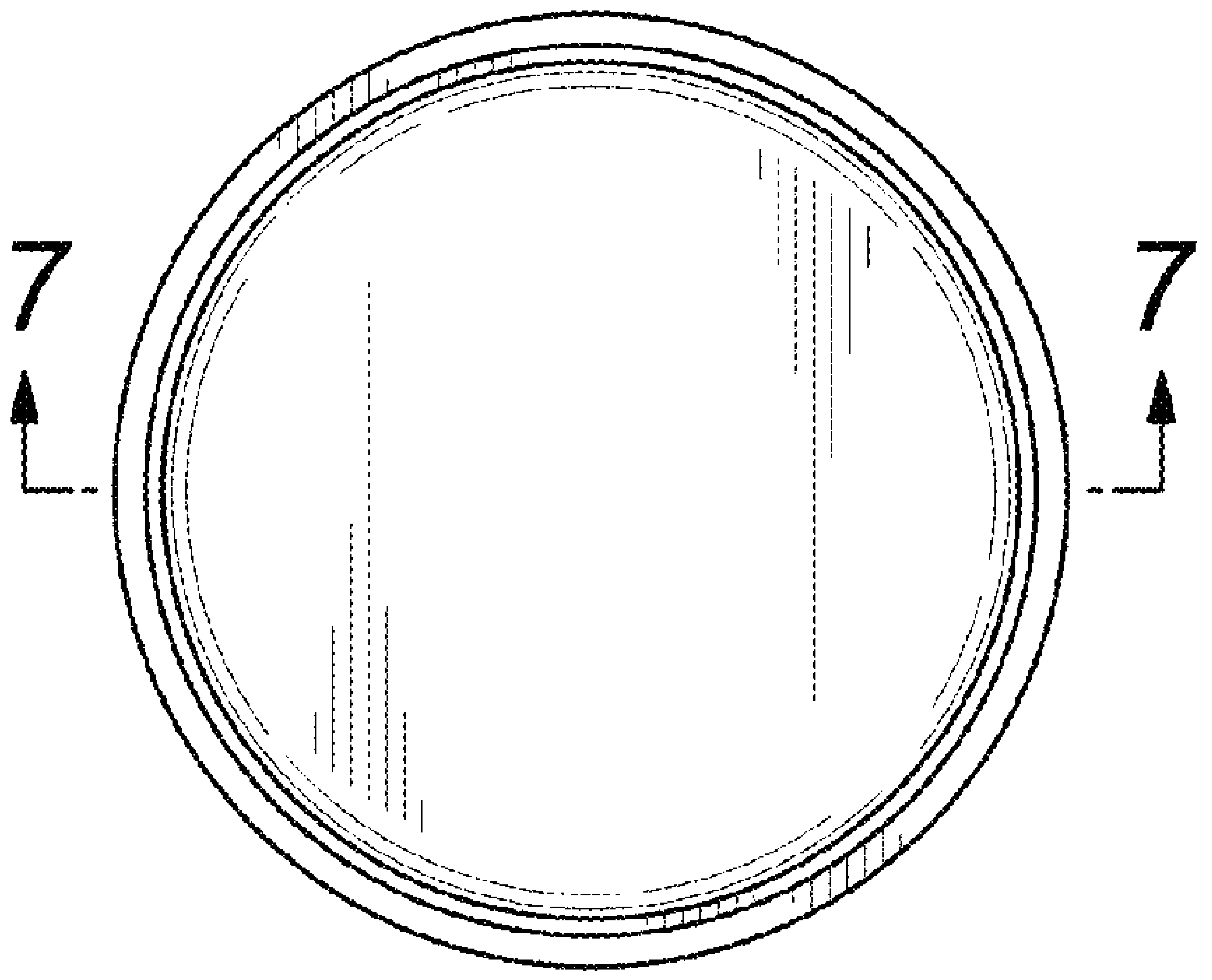


FIG. 5

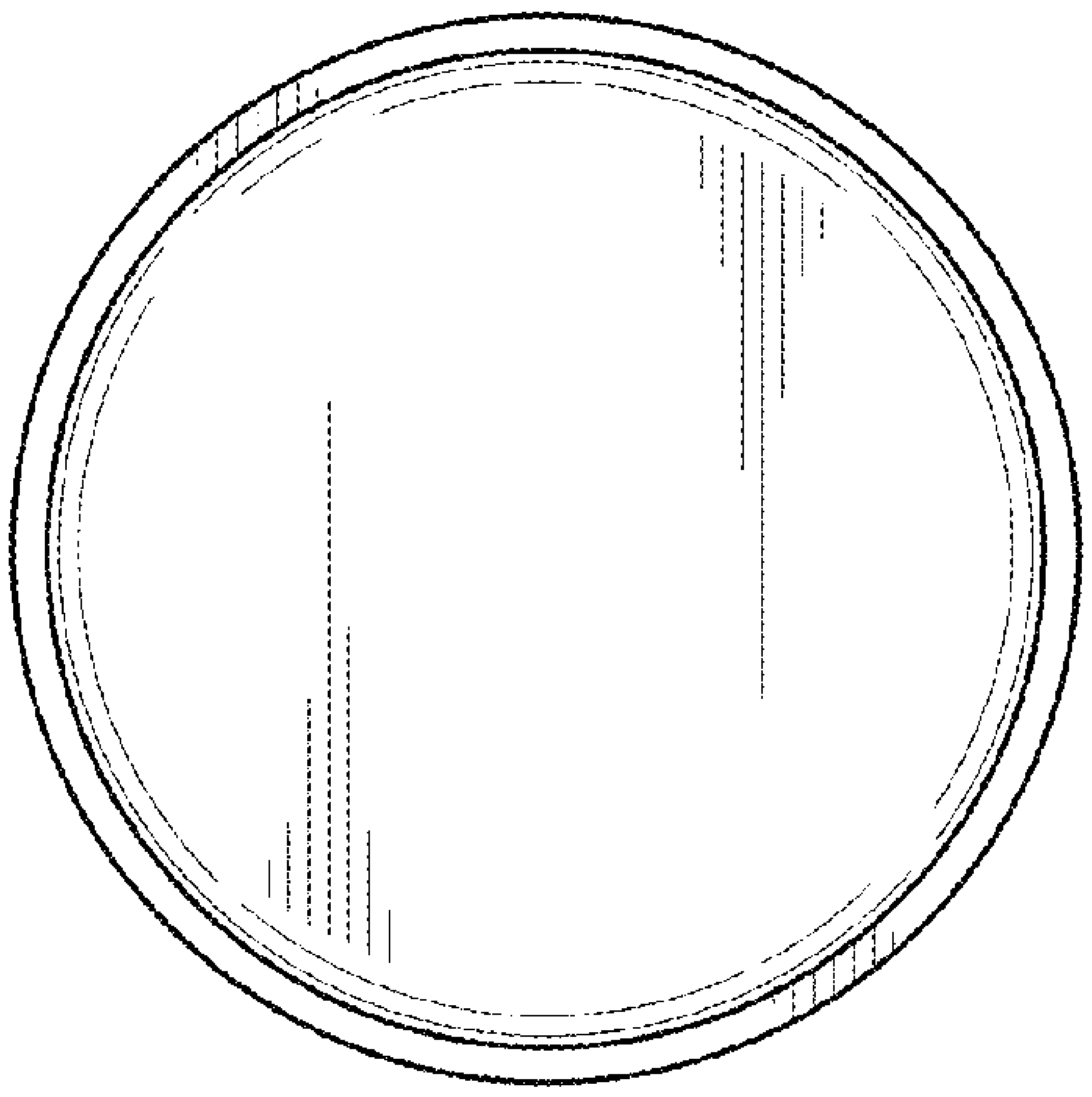


FIG. 6

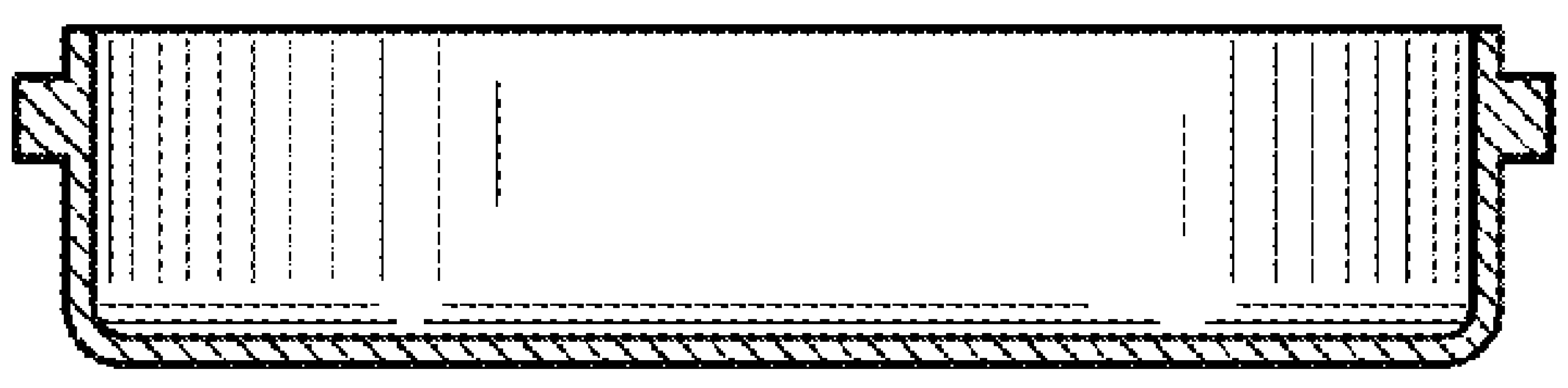


FIG. 7